

■ Application

The mode to handle gases having hazardous ingredients used in the semiconductor LCD, LED, OLED, SOLAR process using arc plasma. All types of gases including PFC gas can be handled.



■ General Features

- ▶ High Reliability
- ▶ High active thermal ARC Plasma Flame
- ▶ Prevent waste gas recombination
- ▶ pH auto control
- ▶ Tool Interface run mode
- ▶ Easy maintenance design
- ▶ Anti corrosion reactor

■ Utility Requirements

Item	Specification
Dimension	850(W)×895(D)×1700(H)
Electric Power	3Phase, AC208V
Inlet Port	NW40Flange*4Port
CDA	1/2" Lok, 5~6.5kgf/cm ²
N ₂	1/2" Lok, 3~5kgf/cm ²
PCW	1/2" Lok, 4~5kgf/cm ² , Supply&Return
CW	1/2" Lok, 3~5kgf/cm ²
NaOH	1 1/2" Double Pipe
Exhaust	MF100Flange, -30 ~ -80mmH ₂ O
Cabinet Exhaust	MF100Flange, -30 ~ -80mmH ₂ O
Drain	15A(PVC)